Special Issue

MEMS/NEMS for Neuroscience

Message from the Guest Editor

Micro and Nano Electromechanical Systems (MEMS/NEMS) are increasingly used in a variety of applications in the field of neuroscience. Studies on single neurons, networks of cultured neurons and organoids, small model organisms, brain mapping, and stimulation have been greatly benefited by the use of microfluidic/lab-on-chip systems, neural probes, implantable biosensors, and microactuators. Key element of MEMS technology is its ability to interact with neurons and neuronal tissue through mechanical, optical, chemical, or electrical means with a high spatiotemporal accuracy. This Special Issue seeks to highlight recent advances of MEMS/NEMS technology in the field of basic and applied neuroscience, at the cellular and organism level. MEMS/NEMS tools for manipulating neuronal activity *in vitro* or *in vivo* are of special interest.

Guest Editor

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Deadline for manuscript submissions

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